



SPA-LEED pattern measured during Homoepitaxial Growth of Si on Si(111)

in H₂ at:

p = 5 × 10⁻⁷ mbar, T = 520 °C, E = 75.6 eV.

(M. Horn-von Hoegen and A. Golla, Surf. Sci. Lett. 337 (1995) L777-82)

Cover picture of Omicron Newsletter I/97

